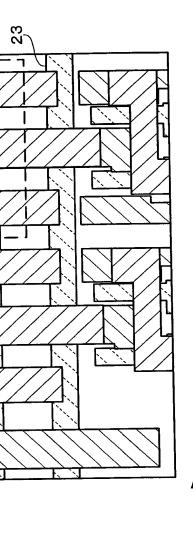
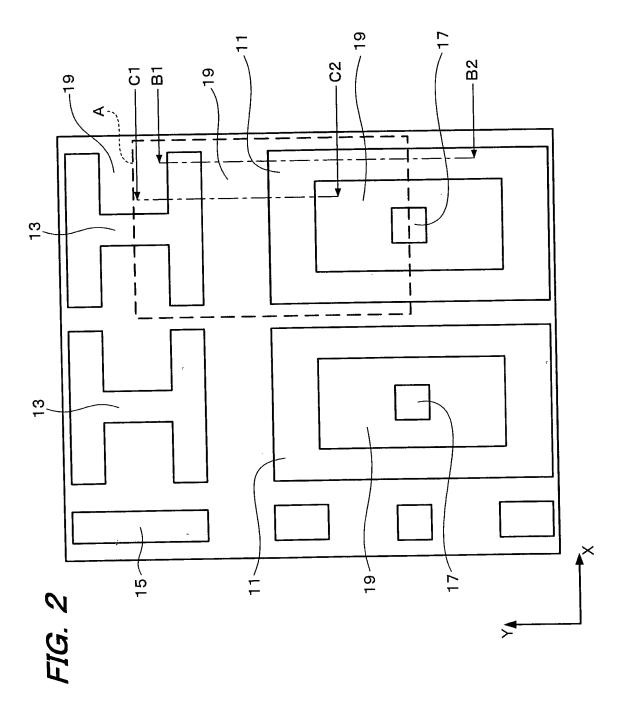
_31a |-31b -21a -41b 43 A Š ö 4<u>1</u>a FIG. 1



, O

Q



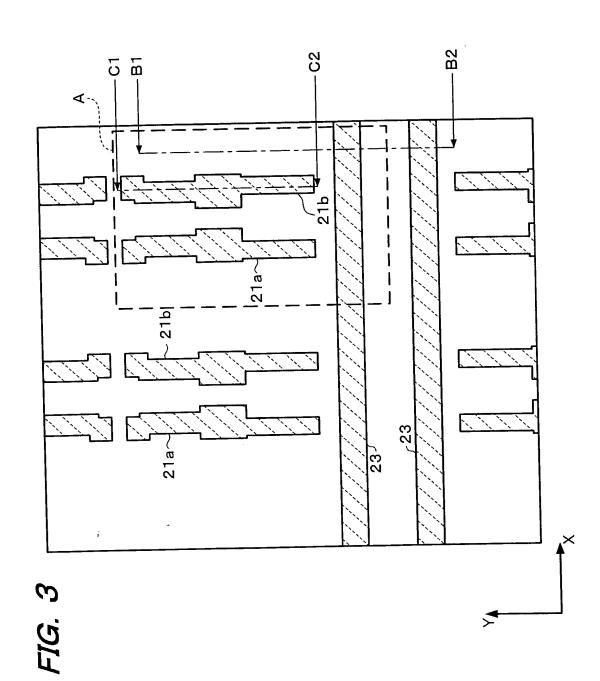
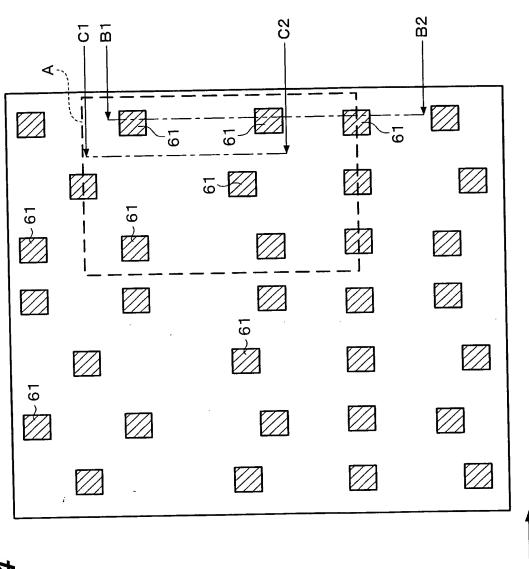


FIG. 4



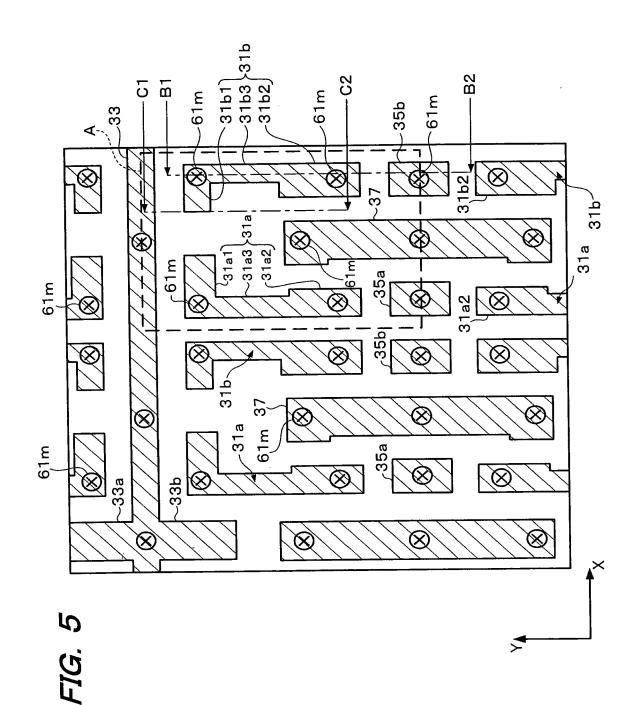


FIG. 6

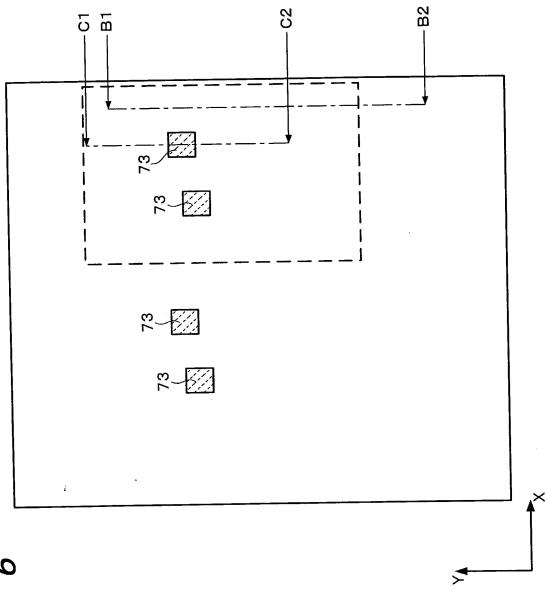
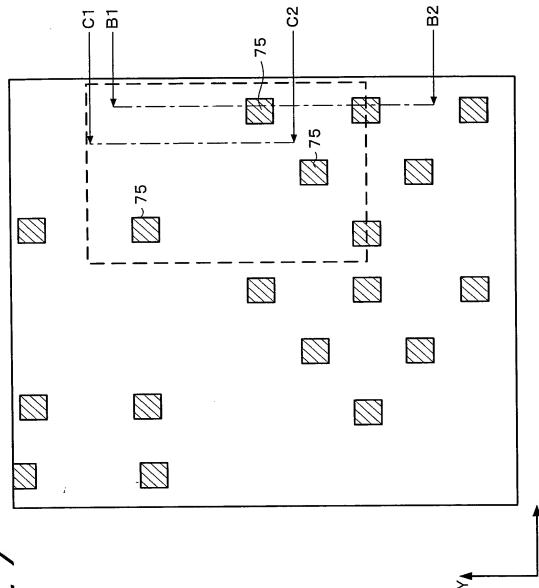
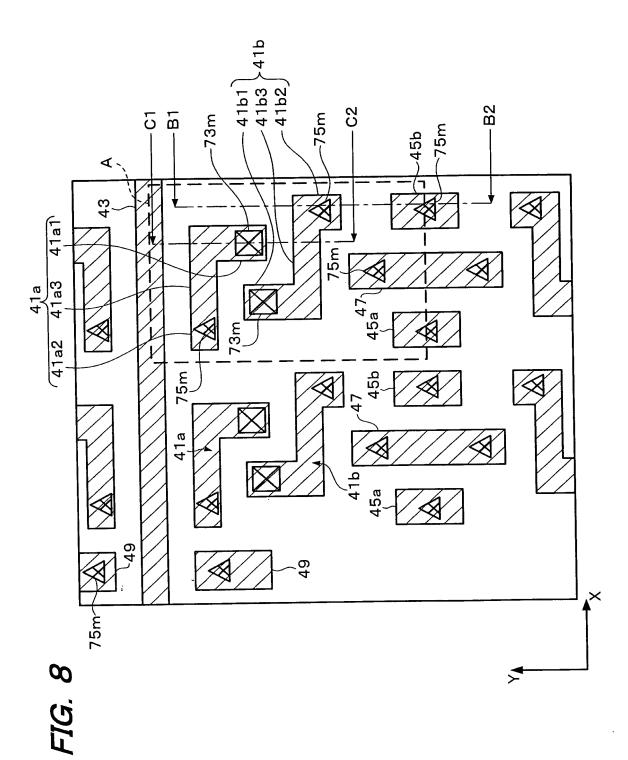
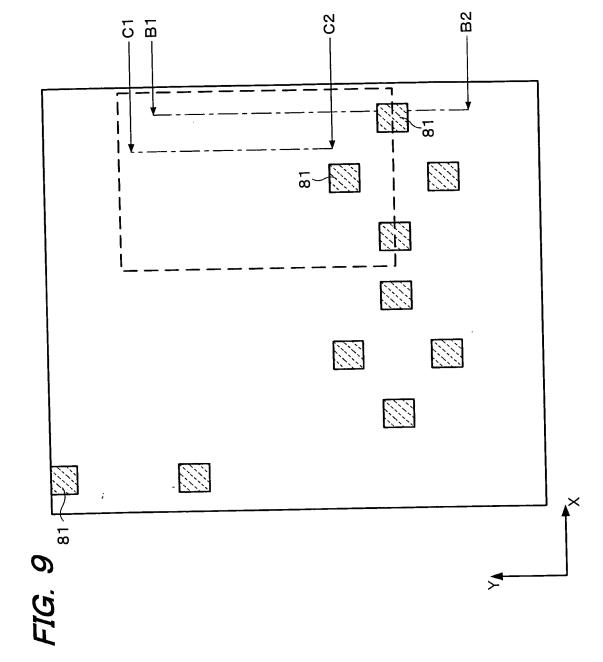
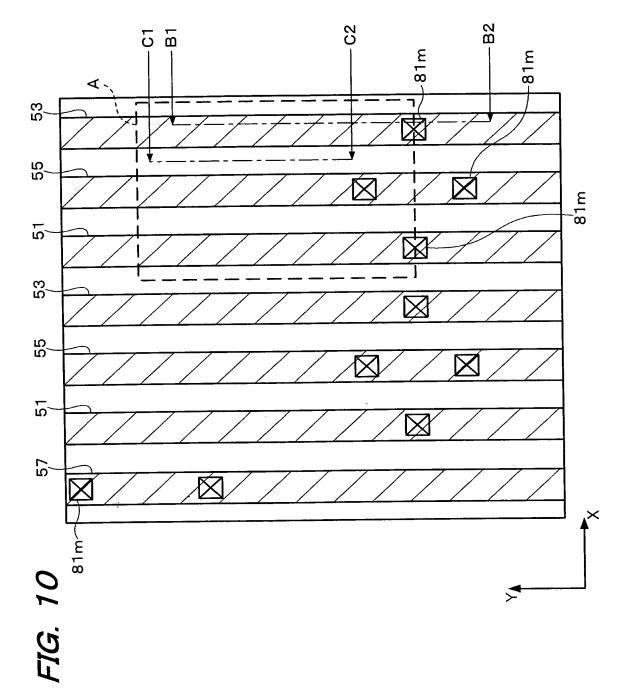


FIG. 7









·B2 -C1 61 -61 -61 13a 61 13a la! 61 15a 23 23 FIG. 11

31a FIG. 12

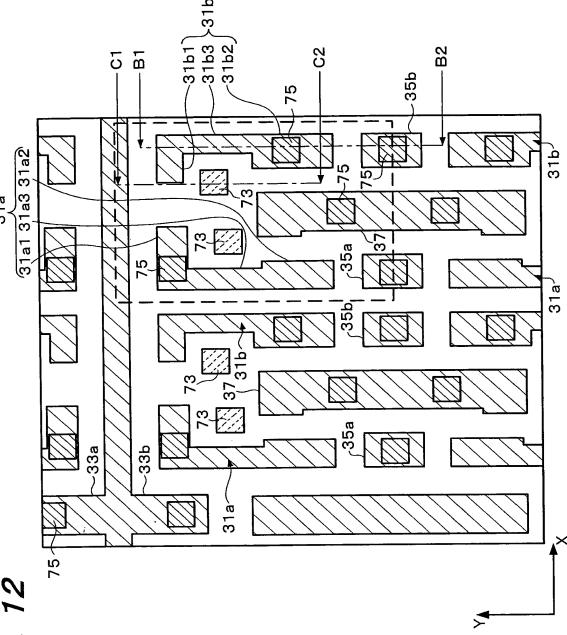


FIG. 13

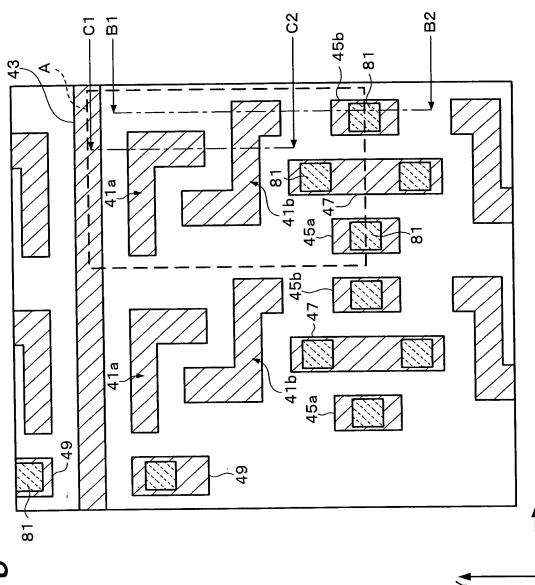


FIG. 14

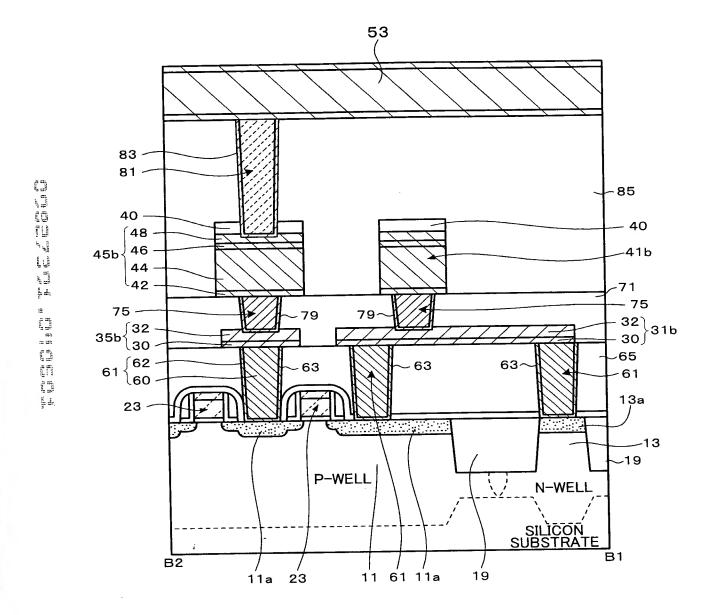
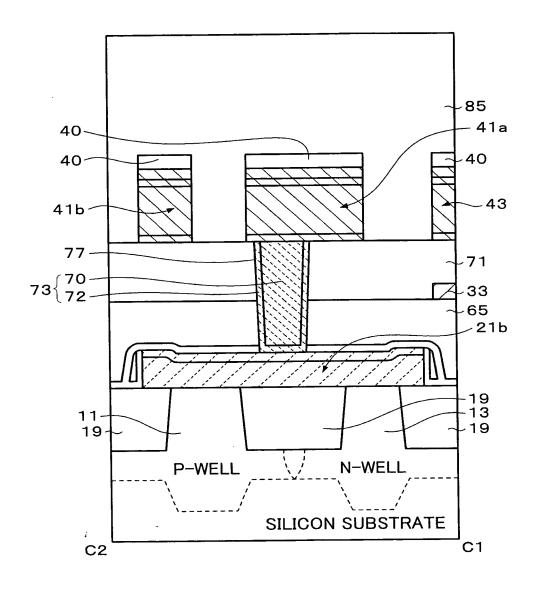


FIG. 15



- 71 - 31b . 85 75 197 1 65 194 - 53 <u>0</u> SILICON SUBSTRATE P-WELL 23 **B**2 23-75 35b. 45b-6 <u>~</u> 83 . 65 .91 485 87 7 95 . 93 8 9 P-WELL 90 25 FIG. 16 19 1 90 96 81 87 1 92 -94

FIG. 17

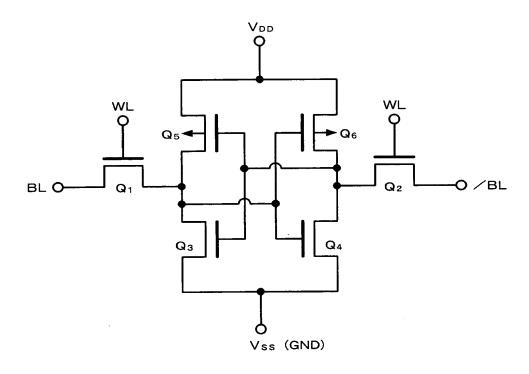


FIG. 18

